

## **Session 4: Micrometrology**

### ***Silicon Styluses for the use in Micro Metrology***

T. Krah, T. Lorenz, A. Phataraloaha, S. Buttgenbach. *University of Technology Brunswick, Germany.*

### ***Automated Microfactory inside a Scanning Electron Microscope***

V. Eichhorn, S. Fatikow, C. Dahmen, C. Edeler, C. Stolle, D. Jasper. *University of Oldenburg, Germany.*

### ***High-Speed AFM Imaging through Adaptive Scanning***

D. Zhang, X. Qian. *Illinois Institute of Technology, U.S.A.*

### ***Cantilever Array with Digital Holographic Readout as Gas Sensor***

L. Sache. *Nyon, Switzerland*; H. Bleuler. *EPFL Lausanne, Switzerland.*

### ***Importance of Metrology in Micro-machine Tools***

E. Buice, J. Ellis, H. Langen, R. Schmidt. *Delft University of Technology, The Netherlands.*

### ***Visual On-line Measurement in a Laser Micro Lathe***

T. Prusi, R. Heikkila, R. Tuokko, A. Vuola. *Tampere University of Technology, Finland*; J. Uusitalo, *VVT Technical Research Centre of Finland, Finland.*